NEPP Electronic Technology Workshop 2012



Challenges for Radiation Hardness Assurance (RHA) on Power MOSFETs

Jean-Marie Lauenstein

Radiation Effects and Analysis Group NASA Goddard Space Flight Center Greenbelt, MD 20771 USA

Acknowledgments



Government:

- Defense Threat Reduction Agency
- NASA/GSFC Radiation Effects and Analysis Group
 - Ken LaBel, Ray Ladbury, Hak Kim, Anthony Phan, Megan Casey, Alyson Topper,
 Stephen Cox, and Tim Irwin
- NASA/JPL
 - Leif Scheick, Steve McClure
- NAVSEA, Crane
 - Jeffrey Titus
- Naval Research Laboratory
 - Dale McMorrow, Stephen Buchner
- European Space Agency
 - Véronique Ferlet-Cavrois, Christian Poivey

University:

- University of Maryland
 - Neil Goldsman, Akin Akturk, and Siddarth Potbhare
- Vanderbilt University
 - Ron Shrimpf, Ken Galloway, Robert Reed, Bob Weller, and Shubhajit Mukherjee

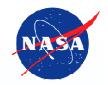




Industry:

- Aeroflex
 - Joe Benedetto
- International Rectifier
 - Sandra Liu, Max Zafrani, and Paul Sherman
- Infineon Technologies
 - Wolfgang Kuebler, Bernd Eisener
- SEMICOA
 - Brian Triggs, Mike Gauthier, and Ahmed Iftikhar
- STMicro
 - Albert Ouellet, Géraldine Chaumont, Hervé Duperray, Patrick Briand
- Tower JAZZ
 - Scott Jordan
- Vishay Siliconix
 - Dave MacDonald, John Demiray, and Arthur Chiang

Introduction



Definition of RHA on power MOSFETs:

 All activities undertaken to ensure that the MOSFET will perform to its design specifications after exposure to the space radiation environment

RHA involves:

- Mission/system/subsystem requirements
 - Power, voltages, current, switching speed, size, quantity, etc.
- Radiation environment definition
 - Low Earth orbit (LEO)? Geosynchronous orbit (GEO)? ...
 - Heavy ion fluence, total ionizing dose (TID) accumulation

Part selection

- Availability, cost, reliability, electrical performance
- and for RHA, single-event effect (SEE) & TID performance

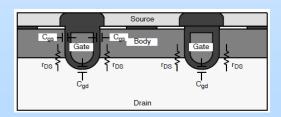
Part testing

- Radiation source parameters, bias conditions, test setup
- Failure rate prediction: method (?)

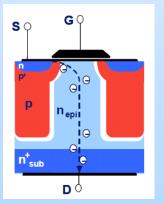
NEPP RHA Focus



- Support test method revision/guideline development
- Evaluate alternative power devices for space applications
 - New technologies
 - New suppliers
- Develop reliable single event gate rupture (SEGR)/ single-event burnout (SEB) rate prediction capability
 - Enhance understanding of failure mechanisms
 - Develop a SEE rate prediction tool



Trench topologies



Superjunction structures



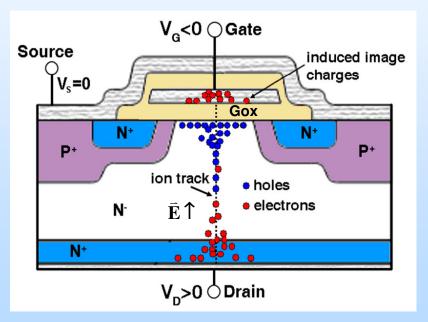
Expected Impact to Community

- Minimize power MOSFET derating penalty (maximize performance) through better failure rate prediction
 - Benefit to designers AND suppliers
- Strengthen existing and foster new relationships with industry
 - Expansion of power device options available for insertion into space applications
 - Development of products that meet the needs of spacecraft and instrument designers
- Streamline test and qualification methods
 - Foster agreement through collaborative efforts
 - Produce meaningful radiation test data

Some Background



- Single-event gate rupture (SEGR) continues to be a key failure mode in power MOSFETs
- SEGR is complex, making rate prediction difficult
- SEGR mechanism has two main components:
 - Gate oxide (G_{ox}) damage
 - Reduces field required for rupture
 - Epilayer response
 - Creates transient high field across the oxide



SEGR in a typical planar vertical power MOSFET (VDMOS)

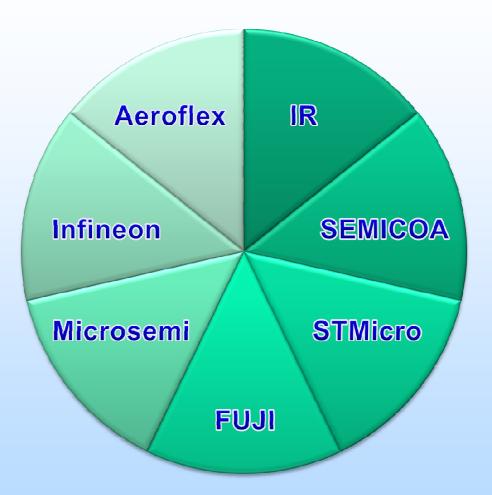


We know our mission requirements and our radiation environment. We are ready for:

PART SELECTION

NASA

Vendors



The number of manufacturers of radiationhardened silicon power MOSFETs is growing

Vendor Datasheets







Table 2. Single Event Effect Safe Operating Area

lon	LET	Energy	Range	V _{DS} (V)					
	MeV/(mg/cm	²)) (MeV)	(µm) @V _{GS}	=0V @V _{GS} =-	5V @V _{GS} =-10)V @V _{GS} =-15\	/ @V _{GS} =-20V	@V _{GS} =-25V
Cu	28	285	43	325	325	325	325	325	325
Br	36.8	305	39	325	325	325	325	320	_

Product Sum	mary		CAGR		_		
Part Number	Radiation Level	RDS(on)	lb	QPL Part Number	17		
IRHM7360SE	100K Rads (Si)	0.20Ω	22A	JANSR2N7391	1.		
International Re	ectifier's RADHard	M HEXEET	® MOS	SEET	TO-254AA	'	
technology prov for space applic	rides high performa cations. This techn performance and	nce power	MOS	FETs a de- Features	vent Effect (SEE) Hard	ened	
	hese devices hav					erieu	

EEE-INST-002: Instructions for EEE Parts Selection, Screening, Qualification, and Derating

Туре	Stress Parameter	Derating Factor
	Power	0.60
All	Current	0.75
(Note 2)	Voltage (Note 1)	0.75
	Junction Temperature 2/	0.80
Power MOSFETs	Gate to Source Voltage	0.60
	Source to Drain Voltage	0.75
	Junction Temperature 2/	0.80

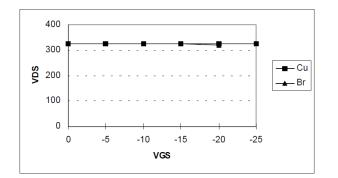


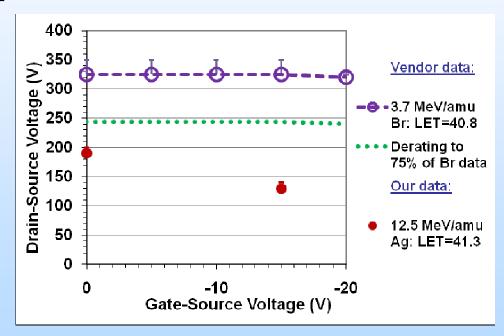
Fig a. Single Event Effect, Safe Operating Area

- Ex/ operation bias needed: gate-source off bias $(V_{GS}) = 0 \text{ V}$ with peak drain-source voltage $(V_{DS}) = 180 \text{ V}$
 - Per NASA EEE-INST-002, V_{DS} derating factor = 0.75; 180 V→ 240 V for "overhead"
- Circuit designer locates part that seems to fit all electrical needs, noting also:
 - JANS-qualified, appears to meet both TID and SEE requirements per Mission Radiation Requirements document prepared by radiation engineer

If Only RHA Were That Easy...



- Power MOSFET SEE data are complex
 - Because the failure mechanisms are complex.
- Linear energy transfer (LET) alone is not the appropriate metric for power MOSFET SEE RHA

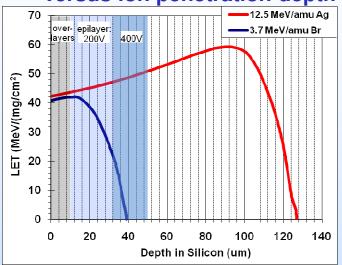


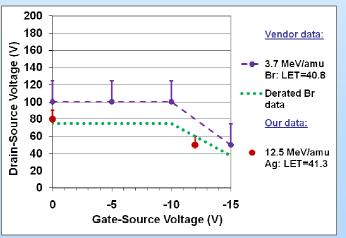
For the same incident LET, irradiation with a different ion yielded SEE failure at a much lower bias for this part

Ion LET vs. Energy



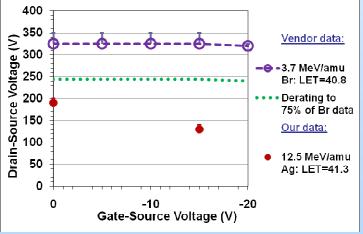
Ion range effects: Energy deposition versus ion penetration depth





For the same incident LET, ions with different energies will deposit different total energy into the sensitive epilayer, yielding different SEGR test results. (see Titus, et al., 1996)

 Example of this ion range effect is shown in a 200V and a 400V vertical power MOSFET (VDMOS):



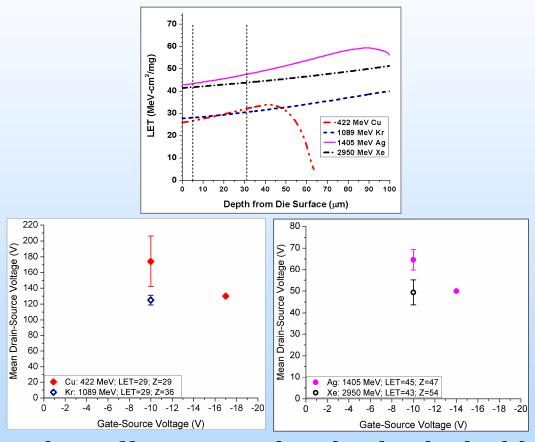
200V VDMOS

400V VDMOS

Ion Species vs. Energy Deposition



Tests controlling for charge ionized in epilayer expose effects of ion atomic number on SEGR failure threshold bias



Ion species effects need to be included in efforts to bound the on-orbit risk of SEGR



Better RHA through improved standards for:

PART TESTING

The Risk Puzzle: Beam Conditions



Ion Energy Spe

Ion Species

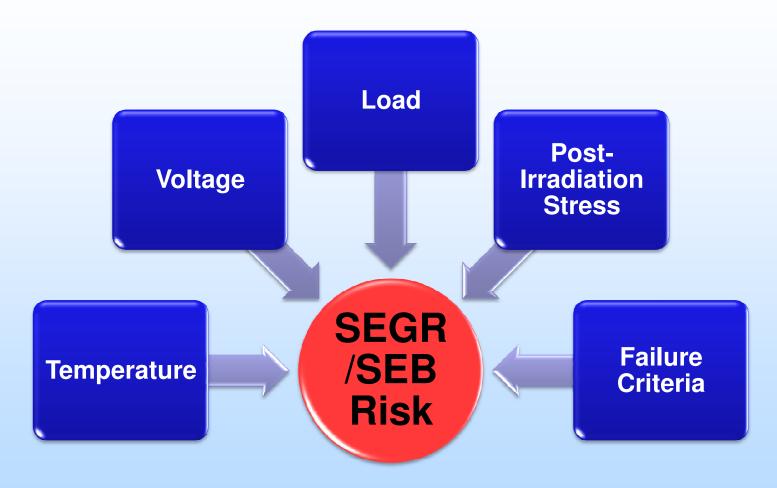
Ion Angle

SEGR /SEB Risk Vacuum /Air

LET is not a piece for bounding on-orbit risk: it can mask other key pieces

The Risk Puzzle: Test Conditions





Test conditions must be specified to enable data comparison

The Risk Puzzle: Device Properties



Structure:

VDMOS, LDMOS, HEMT, Trench, Super Junction, ...

VDMOS: vertical double-diffused

MOSFET;

LDMOS: lateral double-diffused

MOSFET;

HEMT: high electron mobility

transistor

Material:

Si, SiC, GaN, ...



Appropriate beam and test conditions may vary based upon device properties

MIL-STD-750-1 TM1080



Environmental Test Methods for Semiconductor Devices: SEB and SEGR

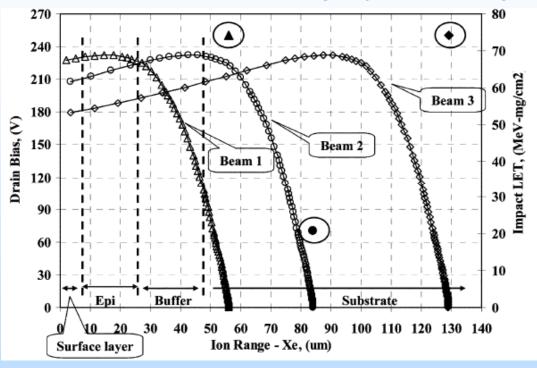
- Revision released this year addresses ion energy/species effects
 - Device "characterization tests are typically conducted to define the worst-case operating conditions"
 - "Ion energy should be considered when determining/defining worst-case test conditions"
- Worst-case (for SEGR) test condition for an ion species:
 - "occurs when the ion fully penetrates the epitaxial layer(s) with maximum energy deposition through the entire epitaxial layer(s)"

TM1080 now specifies an ion range that places the Bragg peak at the epilayer/substrate interface



Worst-Case Ion Range

Failure Vds and Incident LET vs. Xe Range in 500V nVDMOS with Dual Epilayer, at -15 Vgs



Note: Encircled points = Failure Vds per left vertical axis.

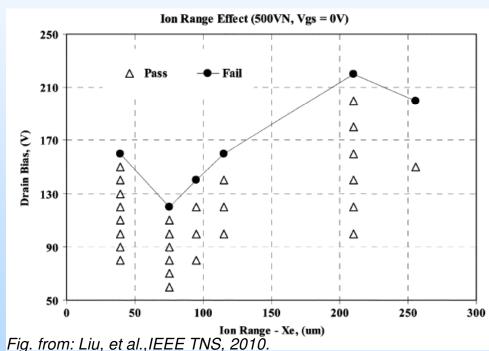
Fig. from: Liu, et al., IEEE TNS, 2010.

 Titus, et al., 2001 first reported on the worst-case ion penetration range and in 2003, suggested a test method based upon this range.

Empirically-Defined Worst-Case Ion Energy: Example



 Worst-case ion range will be the sum of overlayer and epilayer thicknesses, PLUS the ion range at its Bragg peak.



Overlayers: ~ 7 μm Epilayers: ~ 40 μm Xe range at Bragg peak: 31μm

Total: 78 μ**m**

NEPP is involved in developing an ASTM International guideline for power MOSFET testing

Existing Slash Sheet SEEConditions



What about those older lower-energy data?

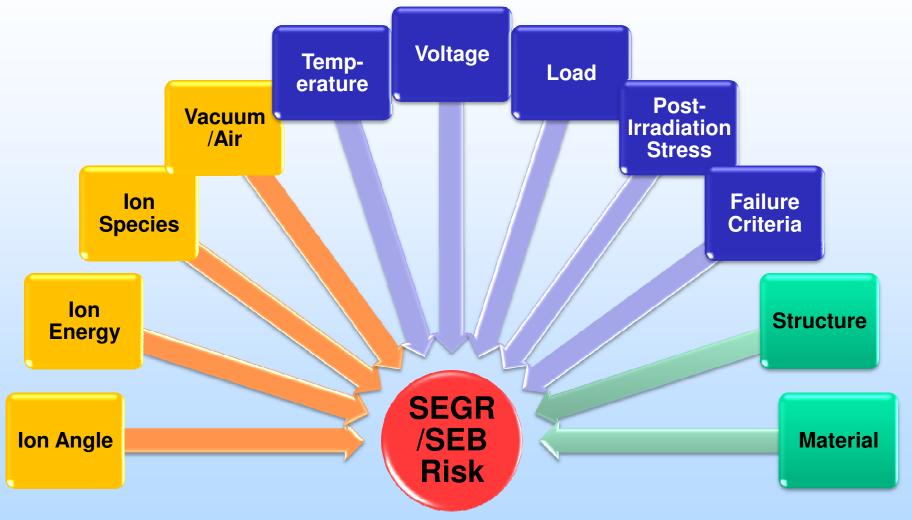
```
LET = 39.4 MeV-cm²/mg, range = 36.5 microns, energy = 292 MeV In situ bias conditions: V_{DS} = 60 V and V_{GS} = -6 V Surface LET = 38 MeV-cm²/mg ±5.0 %, range = 38 µm ±7.5%, energy = 300 MeV ±7.5% (Nominal 3.86 MeV/Nucleon at Brookhaven National Lab Accelerator) In situ bias conditions: V_{DS} = 60 V and V_{GS} = -6 V V_{DS} = 35 V and V_{GS} = -7 V
```

FUTURE: ?

How do we add new vendors to existing slash sheets?

Which Factors Belong in a Slash Sheet?





An active topic at JEDEC Solid State Technology Association JC13.4 ...



How can we use the test data (worst-case or not)?

FAILURE RATE PREDICTION





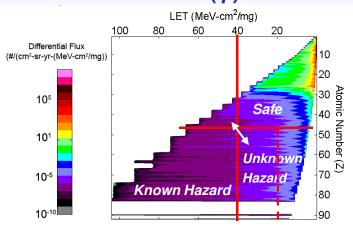
- There is no accepted or verified power MOSFET failure rate prediction method.
- There are several proposed methods for estimating the failure rate:
 - Titus, et al. (1999) prediction of "Early Lethal SEGR Failures" in VDMOS, via Monte Carlo and threshold LET
 - Thales Alenia (Marec, 2009) concept of equivalent LET with use of failure cross section vs. equivalent LET data
 - Edmonds & Scheick (2010) method for including contribution of failures by low-energy ions
 - Lauenstein, et al. (2011) definition of an upper bound on the failure rate considering both ion species and energy

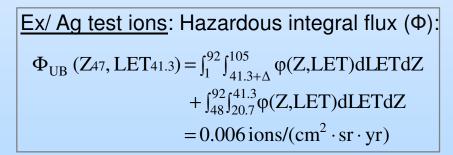
Upper Bound on SEGR Failure Rate

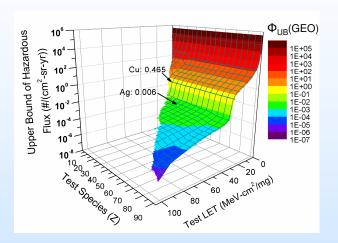


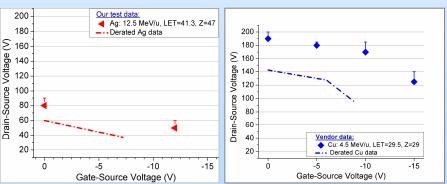
Defining the upper bound (UB) of hazardous flux at a given orbit for a given SEGR response curve: examples for geostationary orbit (GEO)

Differential Flux (ϕ) at GEO









$$\Phi_{\text{UB}}(\text{Zi}, \text{LETi}) = \int_{1}^{92} \int_{\text{LET}_{i+\Delta}}^{105} \phi(\text{Z}, \text{LET}) d\text{LETdZ} + \int_{\text{Zi+1}}^{92} \int_{(\text{LETi}/2)}^{\text{LET}_{i}} \phi(\text{Z}, \text{LET}) d\text{LETdZ}$$

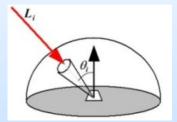
Upper Bound on SEGR Failure Rate (cont'd)



Upper Bound on SEGR Failure Rate Defined From Φ_{UB} :

Rate_{UB} =
$$\Phi_{\text{UB}} \cdot \text{N} \cdot \text{A} \cdot 4\pi (1 - \cos(\theta)) \cdot f$$

- N = # devices to be flown
- A = SEGR cross-section
 - Gate area of die
- θ = max off-normal angle of incidence of SEGR vulnerability
- f = off-state duty cycle



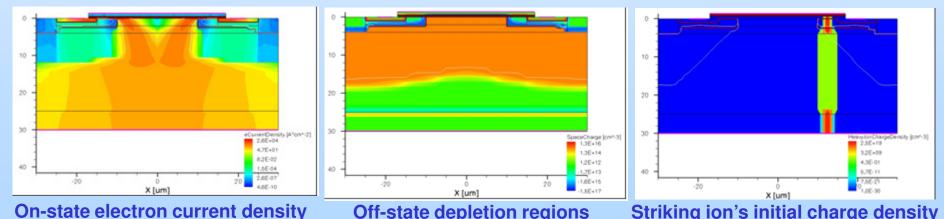
Current form is overly-conservative.

Next step: Refine inclusion of angular effects

Mechanisms of Ion Species **Effects on SEB & SEGR**



- NEPP is involved in enhancing our understanding of power MOSFET failure mechanisms to:
 - Permit failure rate prediction
 - Identify appropriate test methods
- Vanderbilt University graduate student research
 - Explain recent trending of SEB failure thresholds with ion atomic number through detailed modeling of test data
 - Identify mechanisms of oxide damage in SEGR



Off-state depletion regions

27

Conclusions: Power MOSFET RHA



- Good diversification of radiation hardened silicon power MOSFET suppliers
- Test method standards better reflect current research and understanding
- Work still to be done to develop meaningful slash sheets that permit multiple vendors marketing a given part number
- Despite SEGR/SEB discovery in power MOSFETs over 25 years ago, we still don't fully understand the failure mechanisms
 - Many groups actively pursuing power MOSFET SEE research